

IN THE CLAIMS:

Please cancel Claims 1, 4, and 5 without prejudice to or disclaimer of the subject matter recited therein. Please amend Claims 2, 3, 6, and 7 as shown below.

1. (Cancelled)

2. (Currently Amended) ~~A composition for forming a piezoelectric film~~
The method according to ~~claim 1~~, claim 7, wherein said metallic compound is selected from the group consisting of organometallic alkoxides, organometallic complexes, metal organic salts, and metal hydroxides.

3. (Currently Amended) ~~A composition for forming a piezoelectric film~~
The method according to ~~claim 1~~, claim 7, wherein the content of hafnium contained in said composition is 2,000 ppm or less.

4. (Cancelled)

5. (Cancelled)

6. (Currently Amended) ~~A piezoelectric element~~ The method according to ~~claim 5~~, claim 7, wherein the content of hafnium contained in said piezoelectric film ~~held between the lower electrode and the upper electrode~~ is 3,000 ppm or less.

7. (Currently Amended) ~~An~~ A method for producing a piezoelectric film for an ink jet recording head, said ink jet recording head comprising:

a pressure chamber communicating with an ink discharge ~~port,~~ port;

a diaphragm provided in correspondence with said pressure ~~chamber,~~ chamber; and

~~the~~ a piezoelectric element of claim 5 provided in correspondence with the diaphragm,

wherein an ink in said pressure chamber is discharged through said ink discharge port by a change of volume in said pressure chamber caused by the piezoelectric element,

wherein the piezoelectric element comprises the piezoelectric film, and the piezoelectric film is held between a lower electrode and an upper electrode, and

wherein said method comprises the steps of:

coating a substrate with a composition for forming the piezoelectric film, to form a coating film, said composition containing a dispersoid obtained from a metallic compound, and the content of hafnium in said composition being 3,000 ppm or less;

drying the coating film; and

sintering the dried coating film to obtain the piezoelectric film.